

**ABSTRACT**

A sensor apparatus and method are disclosed herein. A base is  
5 generally located proximate to a cover. A sensor element (e.g., quartz,  
silicon, ceramic, and the like) can be located on the base, such that the  
cover and the base form a clearance between the cover and the base. The  
clearance can be configured such that when the cover is at its smallest  
dimension within the tolerance range thereof and the base is at its largest  
10 dimension within the tolerance range thereof there is a clearance between  
them. Additionally, a sensor diaphragm and a dimple can be incorporated  
into the cover, wherein the dimple is in intimate contact with the sensor  
element at all pressure levels and temperatures thereof.